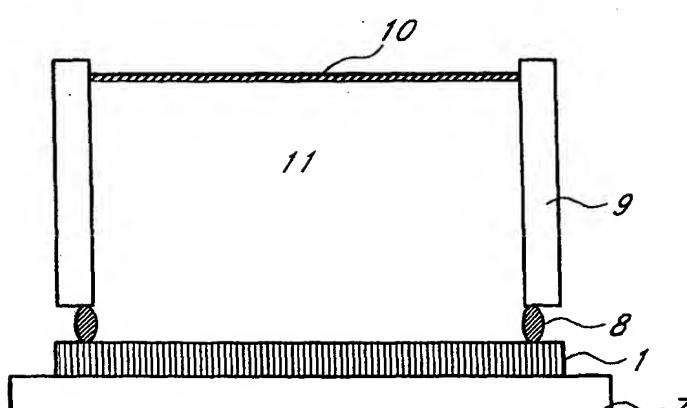
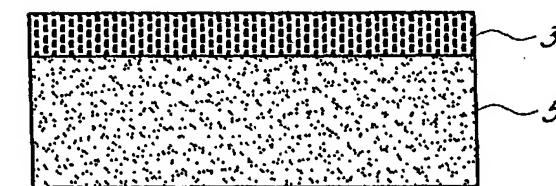
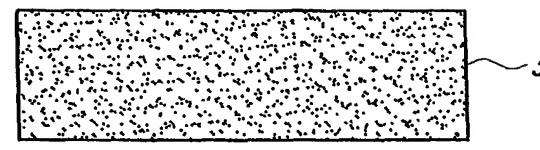
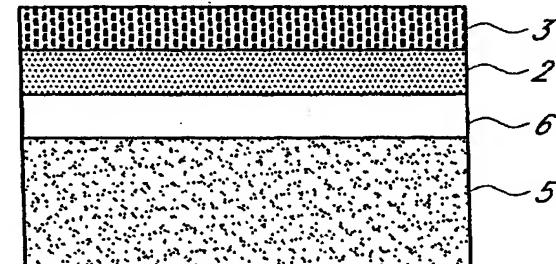
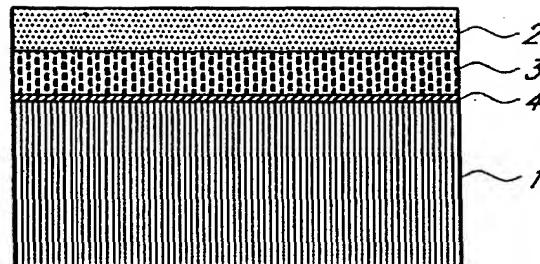
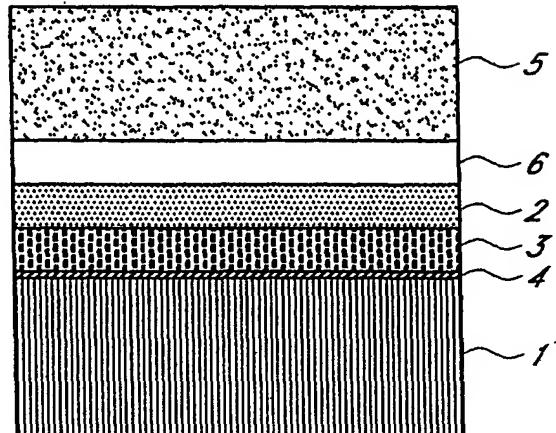
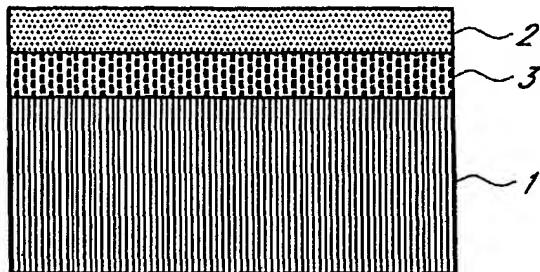


PRIOR ART



*METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
LIFT-OFF OF POROUS SILICON LAYERS*

Solanki, et al.

Appl. No.: Unassigned *Atty Docket: IMEC197.001CP1*

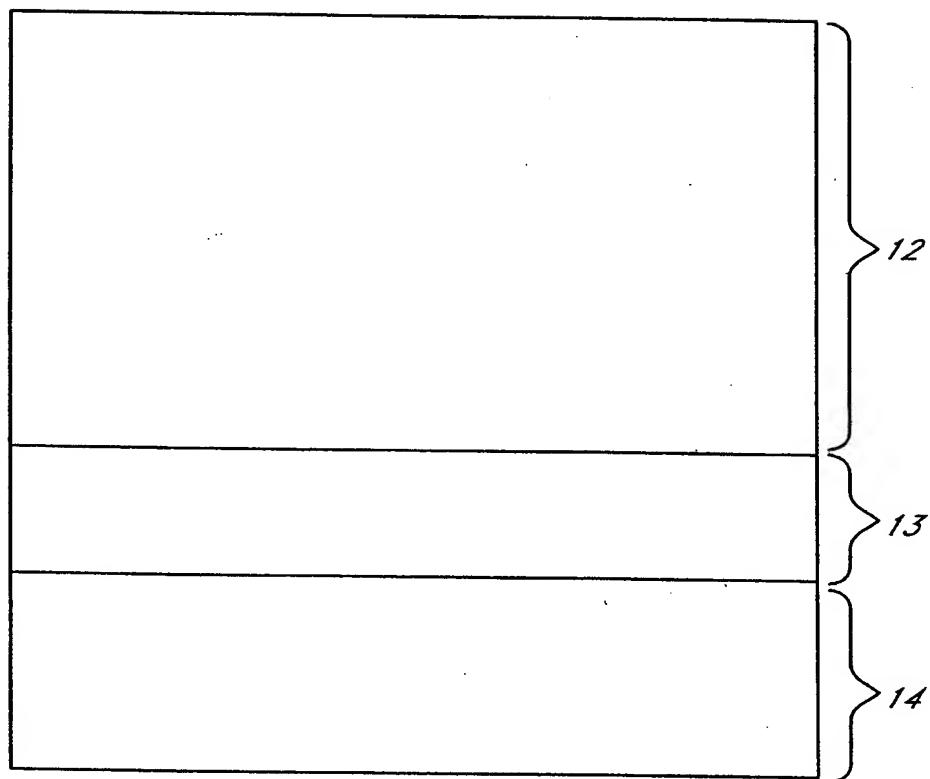


FIG. 3A

METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
LIFT-OFF OF POROUS SILICON LAYERS
Solanki, et al.
Appl. No.: Unassigned Atty Docket: IMEC197.001CPI

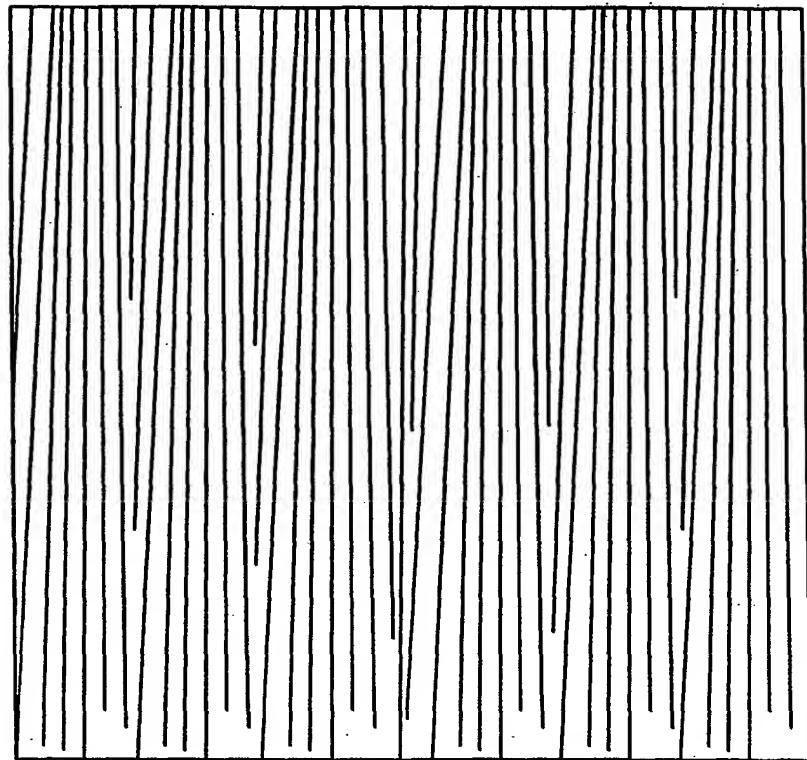


FIG. 3B

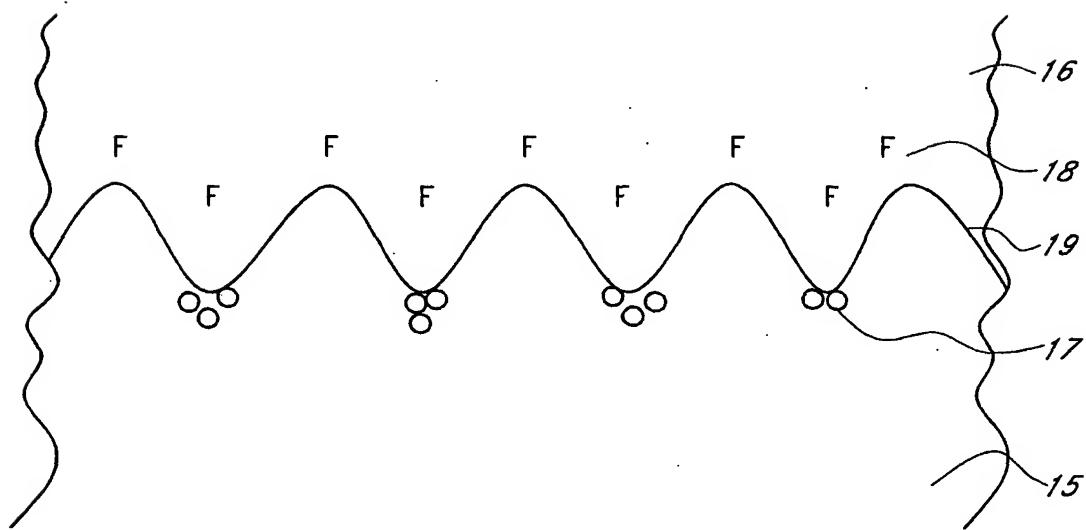


FIG. 4

METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
LIFT-OFF OF POROUS SILICON LAYERS

Solanki, et al.

Appl. No.: Unassigned Atty Docket: IMEC197.001CP1

FIG. 5A

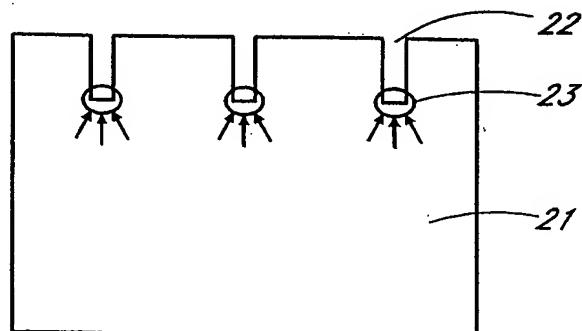


FIG. 5B

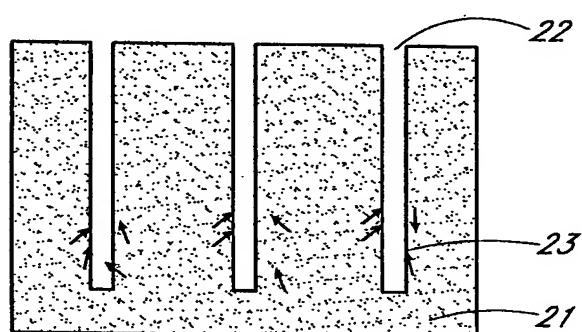


FIG. 5C

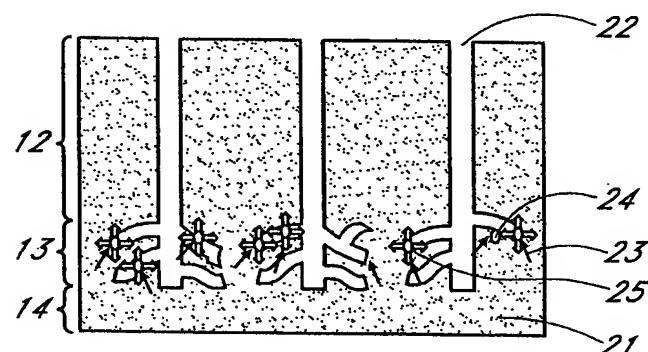
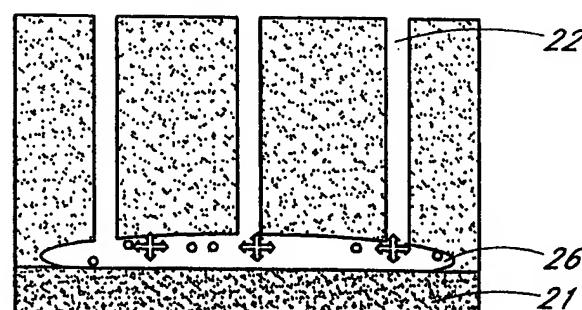


FIG. 5D



METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
LIFT-OFF OF POROUS SILICON LAYERS

Solanki, et al.

Appl. No.: Unassigned Atty Docket: IMEC197.001CP1

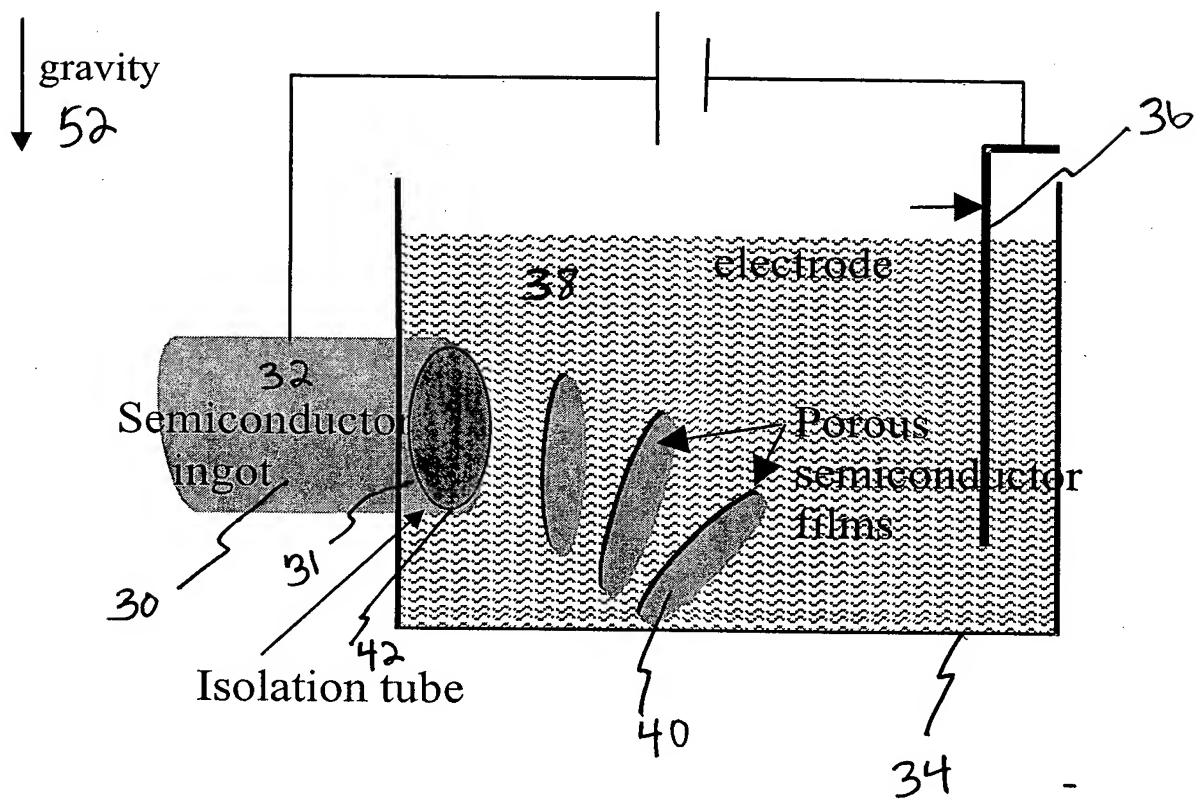
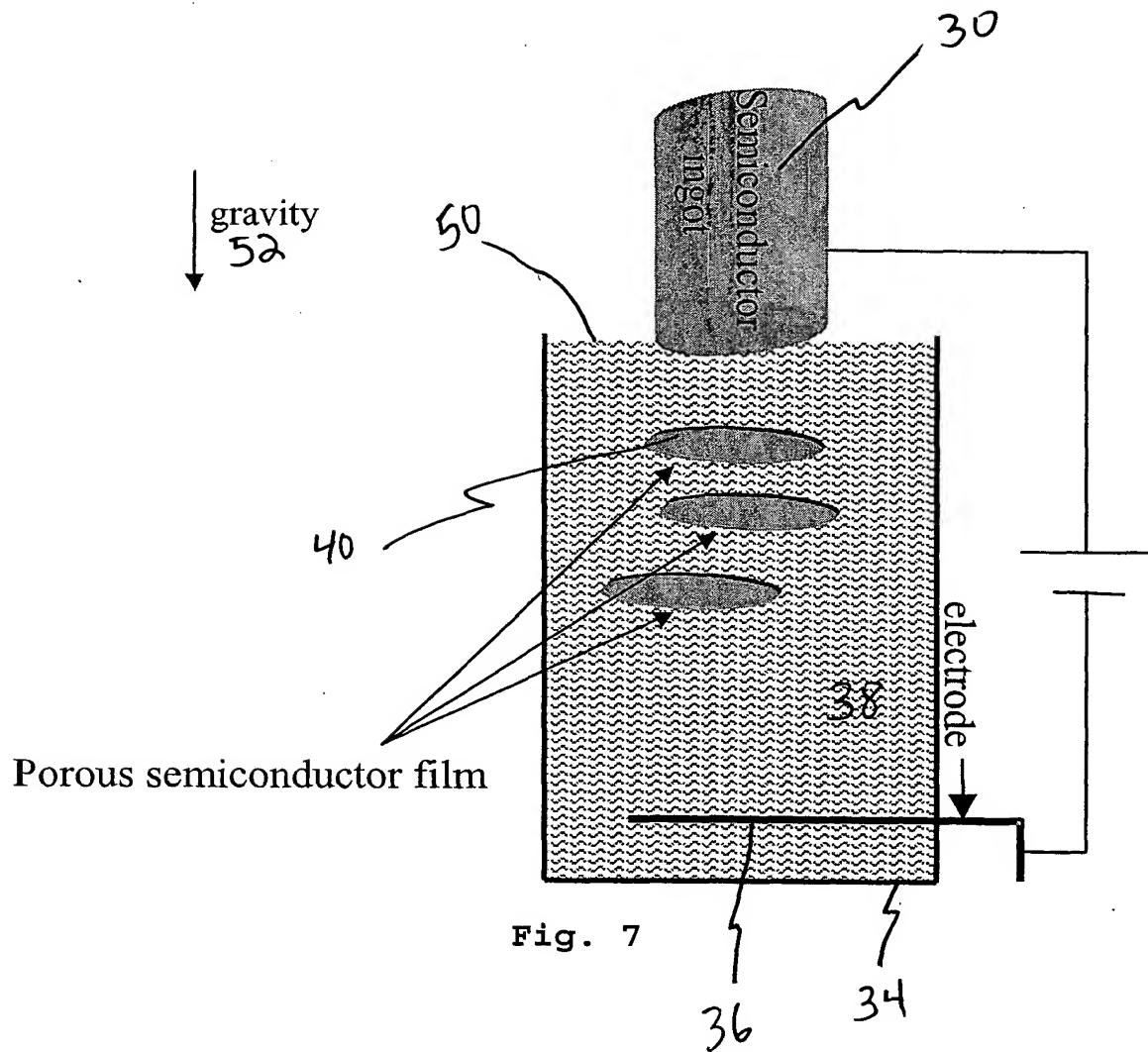


Fig. 6

METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
LIFT-OFF OF POROUS SILICON LAYERS

Solanki, et al.

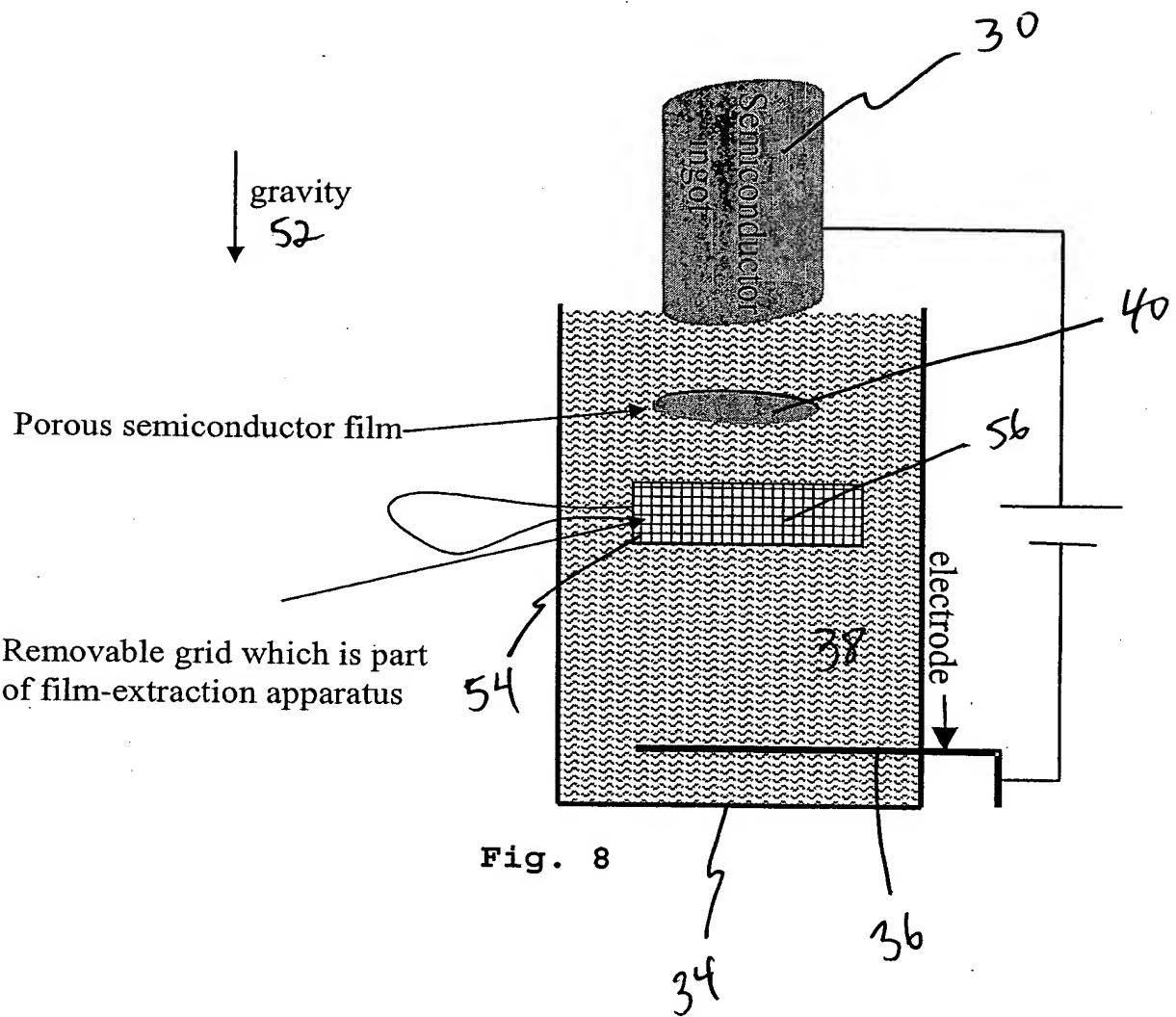
Appl. No.: Unassigned Atty Docket: IMEC197.001CP1



METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
LIFT-OFF OF POROUS SILICON LAYERS

Solanki, et al.

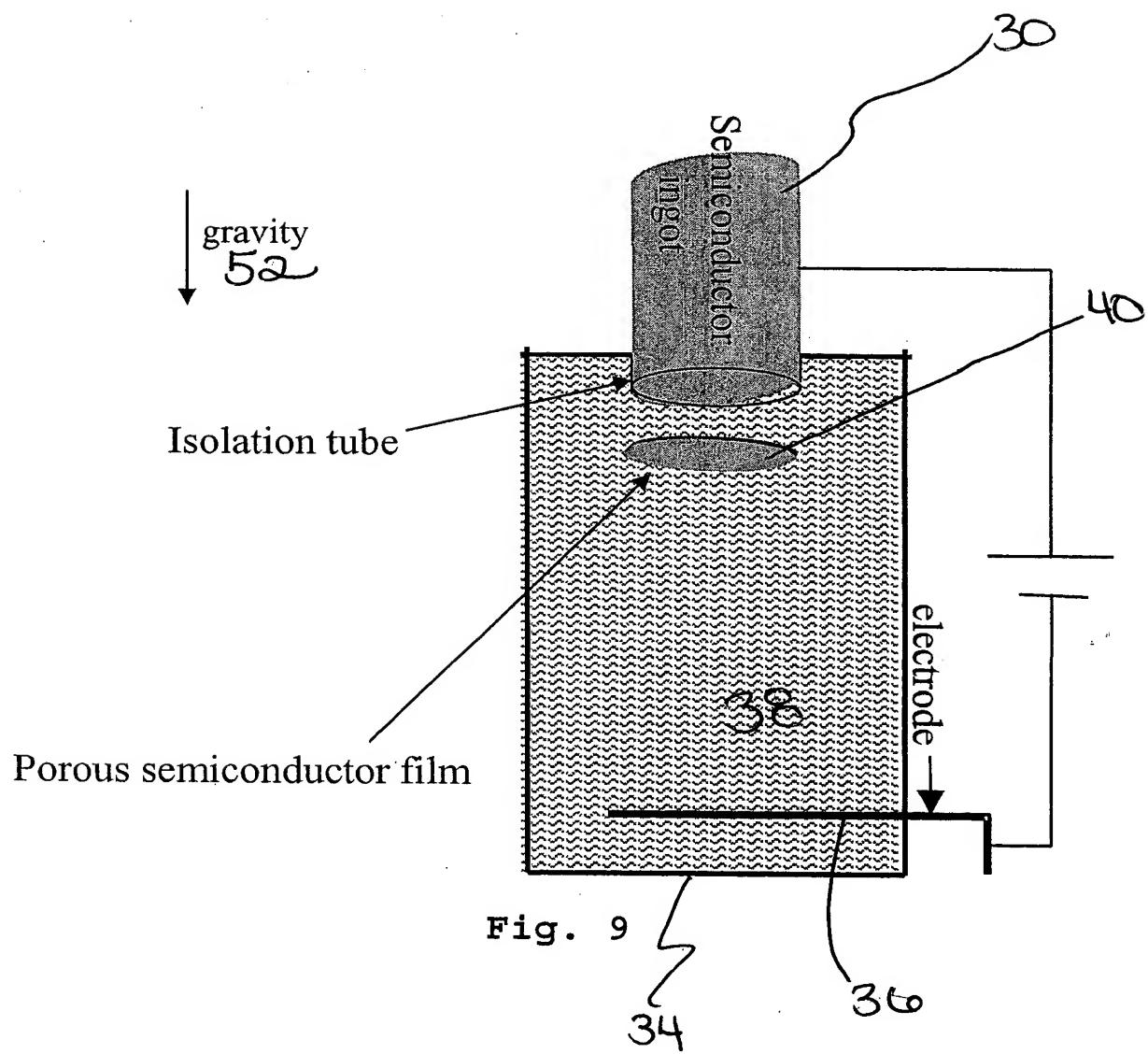
Appl. No.: Unassigned Atty Docket: IMEC197.001CPI



METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
LIFT-OFF OF POROUS SILICON LAYERS

Solanki, et al.

Appl. No.: Unassigned Atty Docket: IMEC197.001CPI



METHOD AND APPARATUS FOR CONTINUOUS FORMATION AND
LIFT-OFF OF POROUS SILICON LAYERS

Solanki, et al.

Appl. No.: Unassigned Atty Docket: IMECI97.001CP1

Fig. 10a

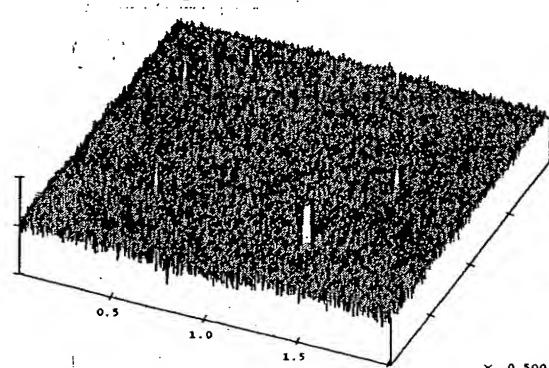


Fig. 10b

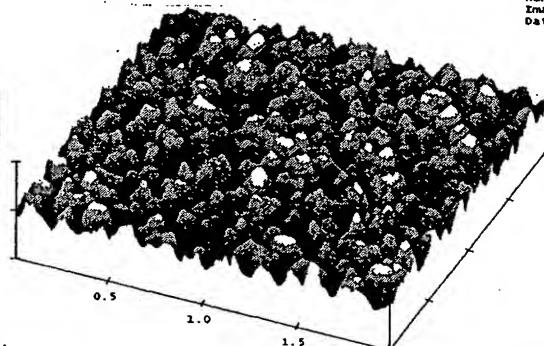


Fig. 10c

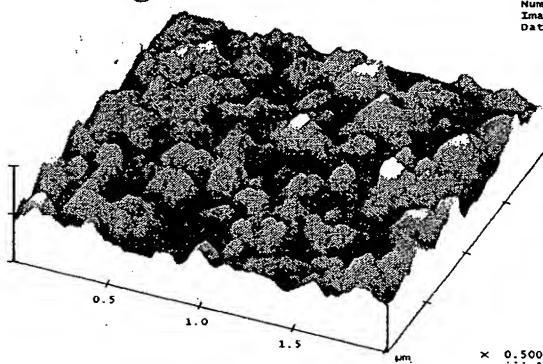


Fig. 10d

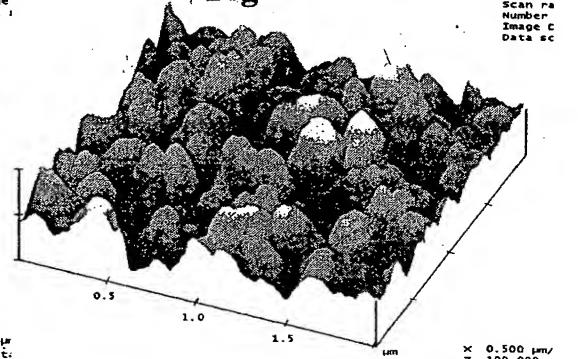


Fig. 10e

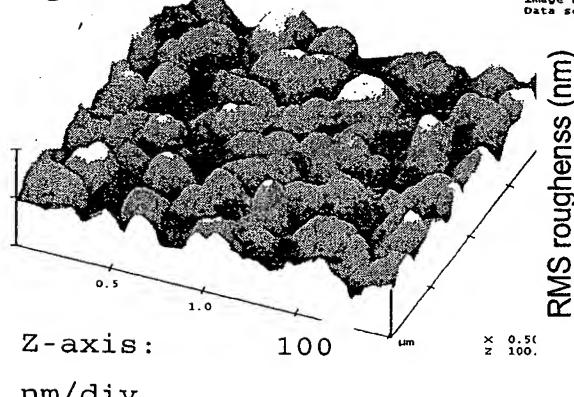


Fig. 10f

